

<b>Notice of References Cited</b>	Application/Control No. 10/729,266		Applicant(s)/Patent Under Reexamination LAIB, GERALD	
	Examiner Michelle (Shelley) Clement		Art Unit 3641	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-2004/0244889	12-2004	Sailor et al.	149/002
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	F	US-			
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	K	US-			
	L	US-			
	M	US-			

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#### NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Hee Cheul Choi and Jillian M. Buriak, POSITIVE AND NEGATIVE PHOTOPATTERNING OF METAL OXIDES ON SILICON VIA BIPOLAR ELECTROCHEMICAL DEPOSITION, <a href="http://www.rsc.org/ej/CC/2001/b104586p">http://www.rsc.org/ej/CC/2001/b104586p</a> (published on the Web 9th August 2001).
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	W	
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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